

Welcome and Introduction

EUV Source Workshop

Hilton Hotel, Santa Clara, CA, USA

Groenplaats Ballroom

February 22, 2004

EUV Source Workshop Organization Committee

Vadim Banine (ASML) Fred Bijkerk (FOM)
Igor Fomenkov (Cymer) Joseph Pankert (Philips Extreme)
Uwe Stamm (Xtreme technologies)
Akira Endo (EUVA) and Koichi Toyoda (EUVA)
Vivek Bakshi (Chair) -ISMT

Presentation Outline

- **Open Conference: Confidentiality Notice**
- **Workshop Purpose**
- **Workshop Agenda**

Public Meeting Notice

This meeting is classified as an “Open Conference” per the U.S. Export Administration Regulations.

- **Confidential or Proprietary information may NOT be disclosed.**
- **All meeting attendees are permitted to take notes or otherwise make a personal record of these proceedings.**
- **Presentations may be available to the public including posting on the International SEMATECH public website.**

Workshop Purpose

- **Review source requirements**
- **Review progress in EUV source performance**
- **Breakout session on following topics:**
 - EUV Source Metrology
 - GDPP vs LPP – time to choose?
 - High Power EUV Source Feasibility

Source Workshop Agenda

TIME

PRESENTATION

PRESENTER

08:00 am Welcome and Introduction

V. Bakshi, ISMT

08:05 am Source Requirements

Y. Watanabe/Canon

Supplier Presentations

*Session Chair: K. Murakami /
Nikon*

08:20 am Cymer

I. Fomenkov

08:40 am EUVA

A. Endo

09:00 am EXULITE

B. Fay

09:20 am JMAR

J. Ricardi

09:40 am PLEX

M. McGeoch

10:00 am **BREAK**

Source Workshop Agenda

TIME

PRESENTATION

PRESENTER

Supplier Presentations (continued)

Session Chair: Y. Watanabe / Canon

10:15 am Philips Extreme UV

J. Pankert

10:35 am PowerLase

S. Ellwi

10:55 am Xtreme technologies

K. Gäbel

Fundamental Data and Modeling

Session Chair; Robert Bristol / Intel

11:15 am Status of Source Fundamental Data

John Gillaspay

11:35 am Recent Results from EUV Source Modeling

A. Hassanein

11:55 am Optics Contamination Workshop Summary

G. Edwards

LUNCH

Source Workshop Agenda

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LUNCH

EUV Source Metrology

01:00 pm

EUV Source Metrology Roadmap

M. Schurmann

01:30 pm

Condenser lifetime measurements

J. Kleinschmidt

01:45 pm

Flying Circus 2, Status and Update

E. Louis

Consortium Research Program

Session Chair: John Gillaspay / NIST

02:00 pm

EUVA

A. Endo

02:15 pm

MEDEA+ and More Moore

Ch. Ziener

02:30 pm

ISMT

V. Bakshi

02:45 pm

Intel

R. Bristol

03:00 pm

BREAK

Source Workshop Agenda

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BREAK Out Sessions

*Session Chair: Bruno Lafontaine
/ AMD*

03:15 pm	On the conversion efficiency of LPP-EUV light source	K. Nishihara
03:30 pm	LPP vs GDPP. Time to Choose?	K. Gabel M. Richardson
04:00 pm	High Power EUV Source Feasibility	J . Pankert I. Fomenkov
04:30 pm	Workshop Summary	V. Bakshi
05:00 pm	Poster Session	
07:00 pm	ADJOURN	

HILTON SANTA CLARA - MAIN LEVEL

Lunch, Posters and Reception

- 1. MONTEREY
- 2. BIG SUR
- 3. MENDOCINO

- 4. SHASTA
- 5. TAHOE
- 6. TRINITY
- 7. YOSEMITE

WORKSHOP

